

Positron microscope

- fast positrons emitted by a β^+ radioisotope
- spatial resolution $\approx 100 \mu\text{m}$ (positron stopping depth)
- non-destructive mapping of spatial distribution of defects

Positron microscope

- mapping of spatial distribution of defects
- microhardness HV
- dislocations (work hardening)

$$HV \approx \sqrt{\rho_D}$$

- grain boundaries (Hall-Petch)

$$HV \approx 1/\sqrt{d}$$

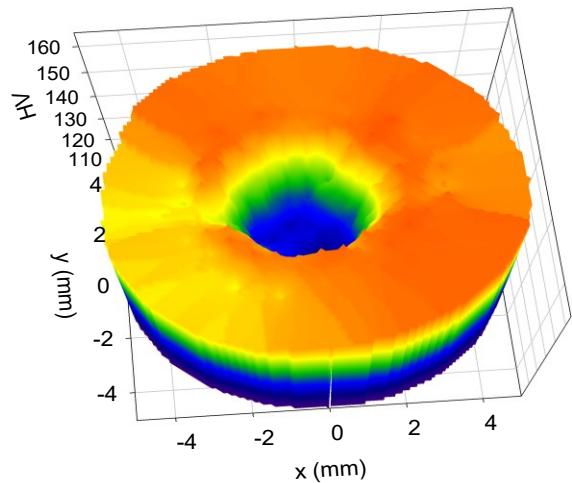
- torsion straining

$$e = \ln(\vartheta r / l)$$

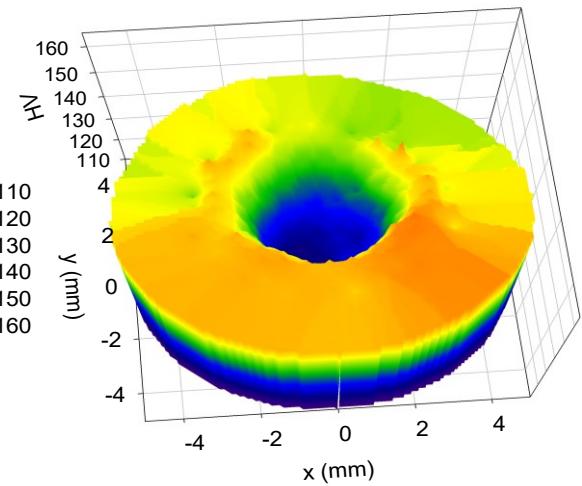
- e – von Misses equiv. strain
- ϑ - rotation angle
- r – radial distance
- l – sample thickness

Ultra fine grained Cu HPT ($p = 6$ GPa)

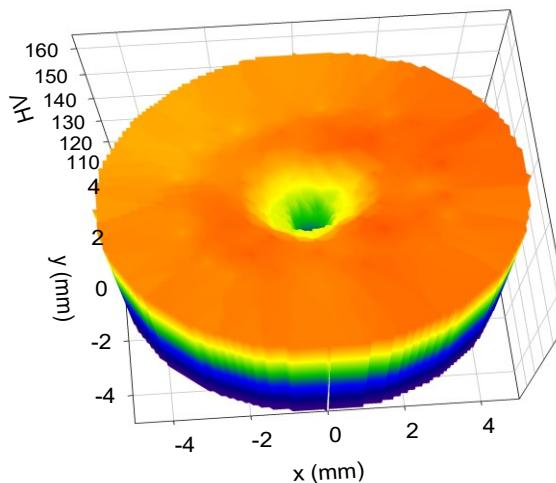
1 HPT revolution



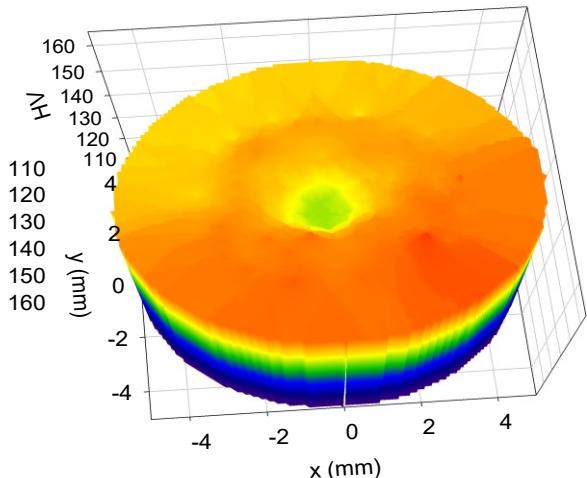
3 HPT revolutions



15 HPT revolutions



25 HPT revolutions



Positron microscope

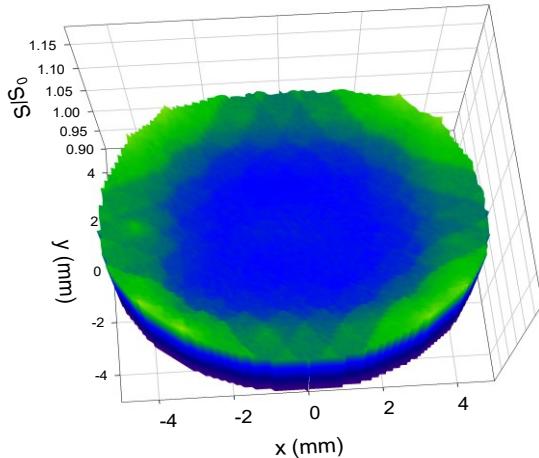
- mapping of spatial distribution of defects
- measurement of Doppler broadening
- S -parameter mapping
 - dislocations
 - grain boundaries
 - deformation-induced vacancies
- torsion straining

$$e = \ln(\vartheta r / l)$$

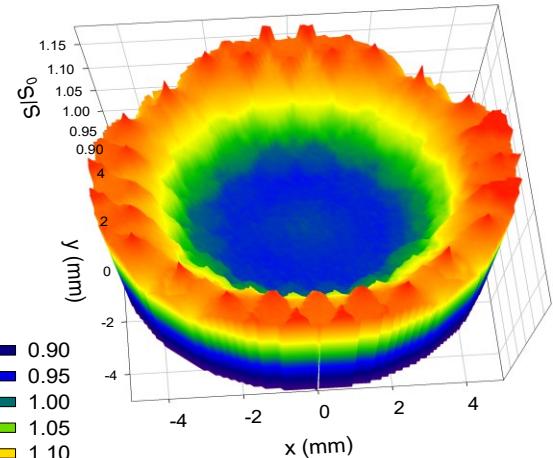
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Ultra fine grained Cu HPT ($p = 6$ GPa)

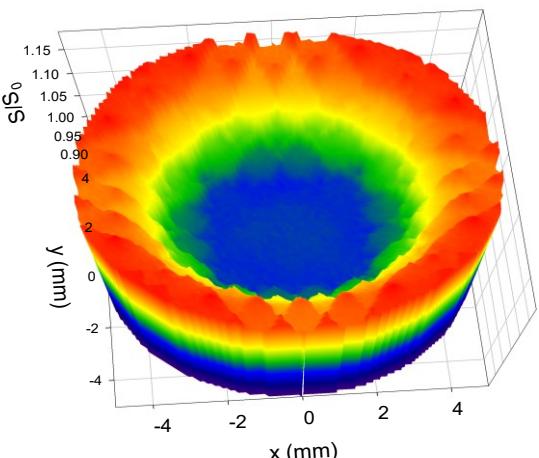
1 HPT revolution



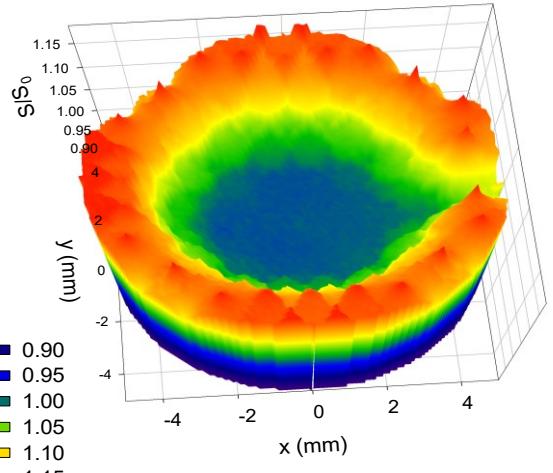
3 HPT revolutions



15 HPT revolutions

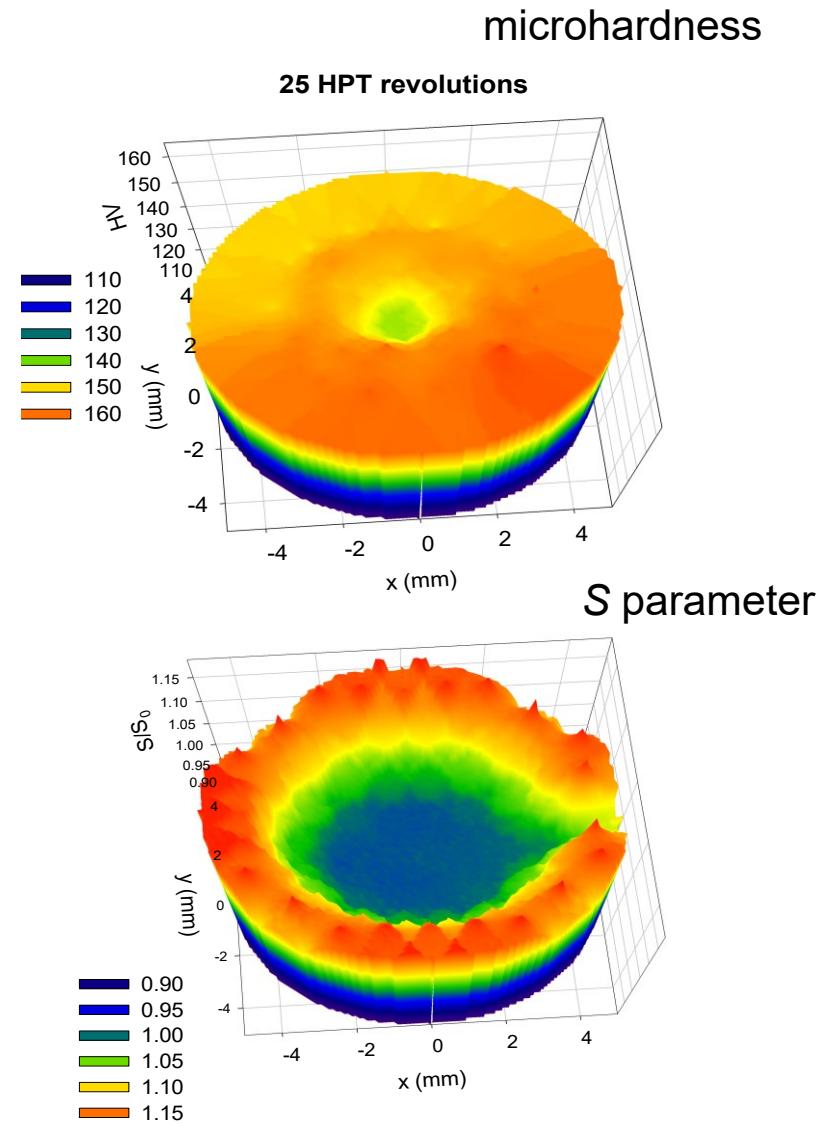
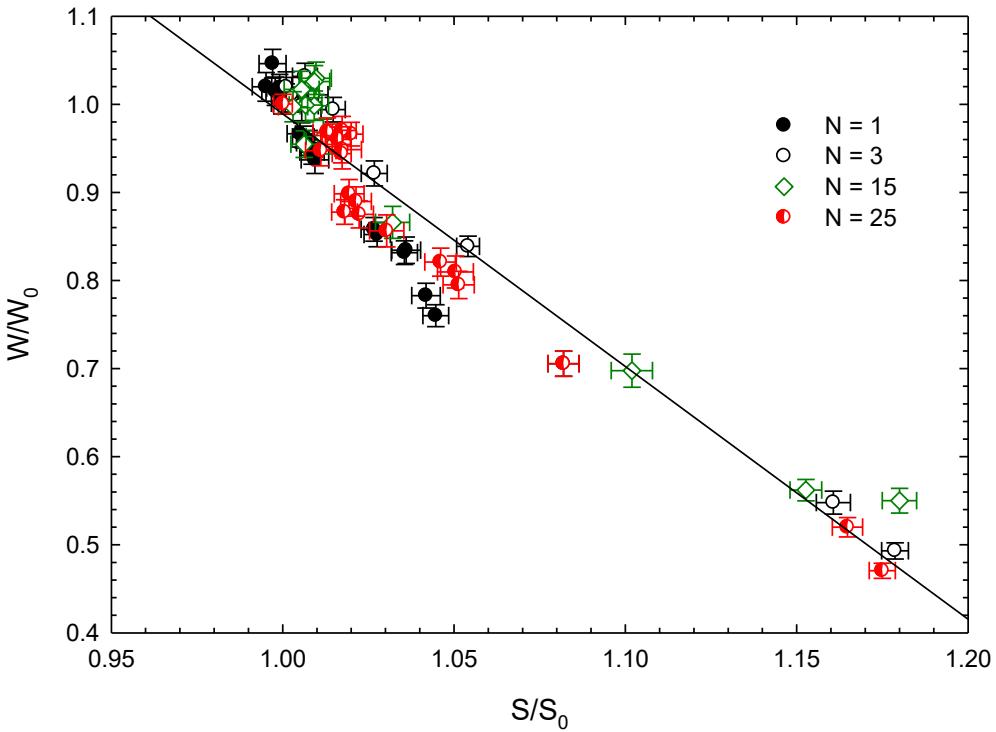


25 HPT revolutions



Positron microscope

- Ultra fine grained Cu HPT ($p = 6 \text{ GPa}$)
- S - W plot



Positron microscope

- slow positrons moderated in a slow positron beam
- the mean implantation depth of $E \approx 1$ keV positrons is $z_{mean} \approx 10$ nm
- spatial resolution is limited by positron diffusion length $L_+ \approx 100$ nm
- mapping of lateral distribution of defects + depth profile of defects
- non-destructive 3D mapping of defect distribution

Positron microscope

- brightness of positron beam

$$B = \frac{I}{\Omega_x \Omega_y}$$

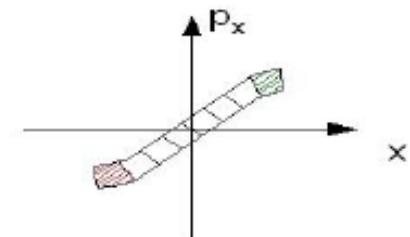
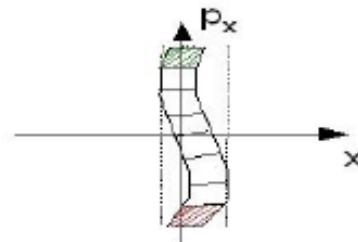
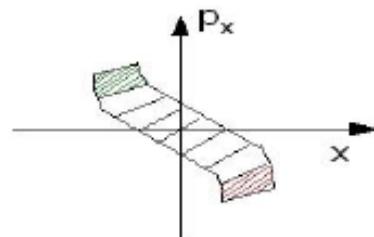
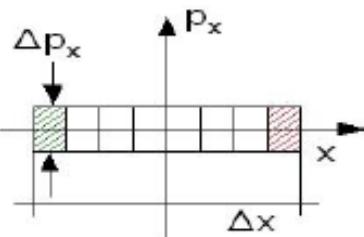
I – intensity

- Liouville theorem

$$\Delta x \Delta p_x = \Omega_x = \text{konst}$$

$$\Delta y \Delta p_y = \Omega_y = \text{konst}$$

- brightness of commercially available e^+ sources is $10^{-19} - 10^{-16}$ the brightness of typical e^- sources!



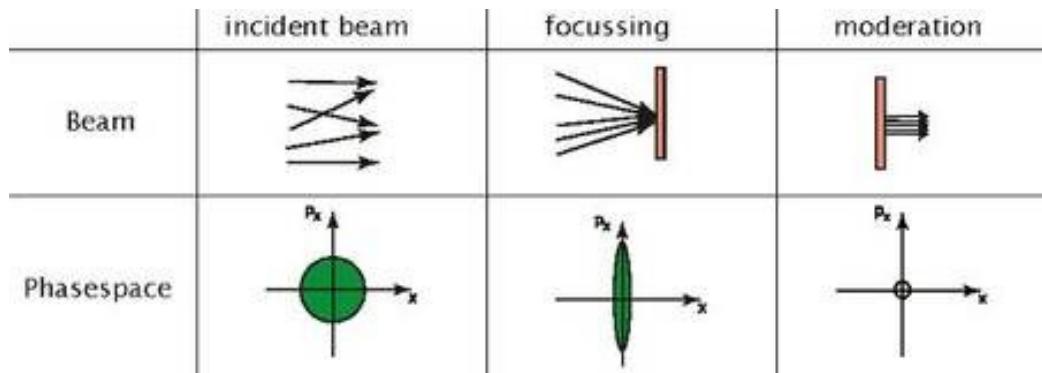
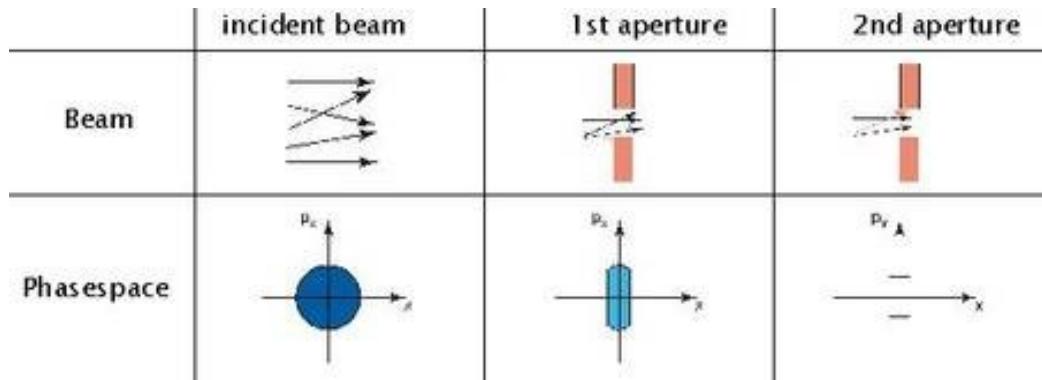
Positron microscope

- remoderation

$$B = \frac{I}{\Omega_x \Omega_y}$$

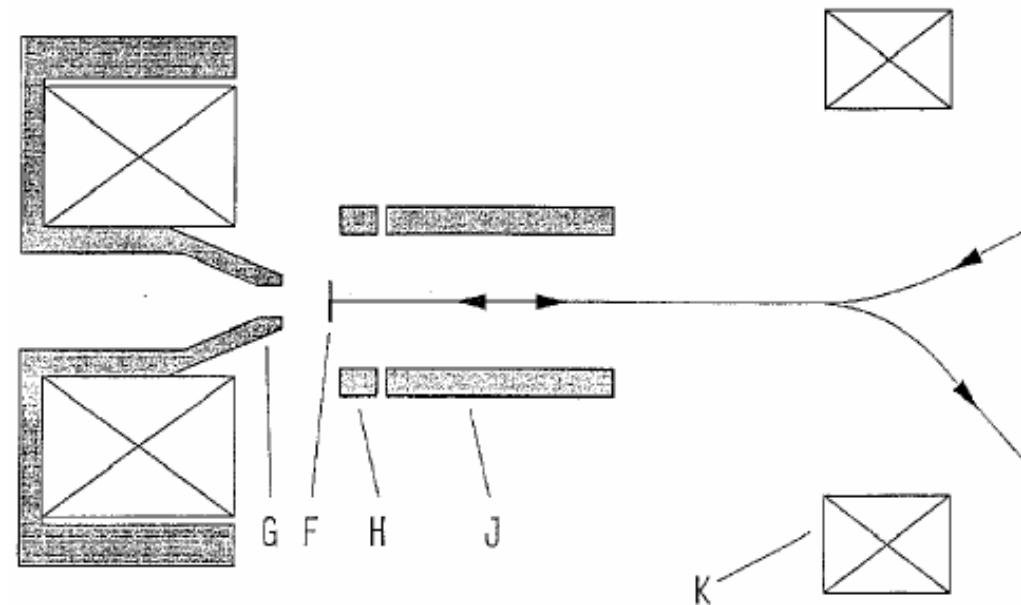
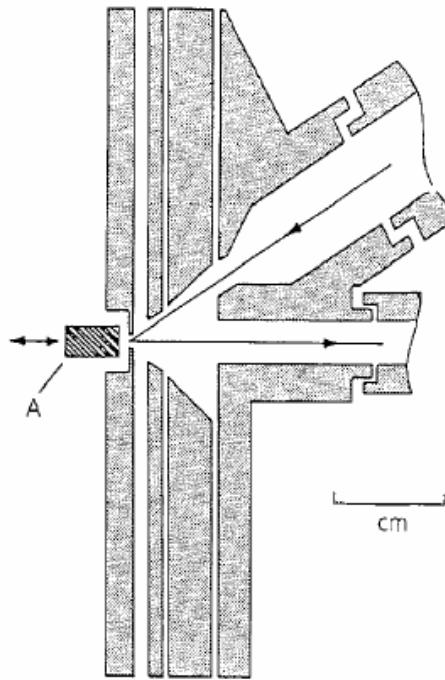
I – intensity

- brightness enhancement
- i.e. reduction of beam volume in the phase space
- inevitable reduction of intensity



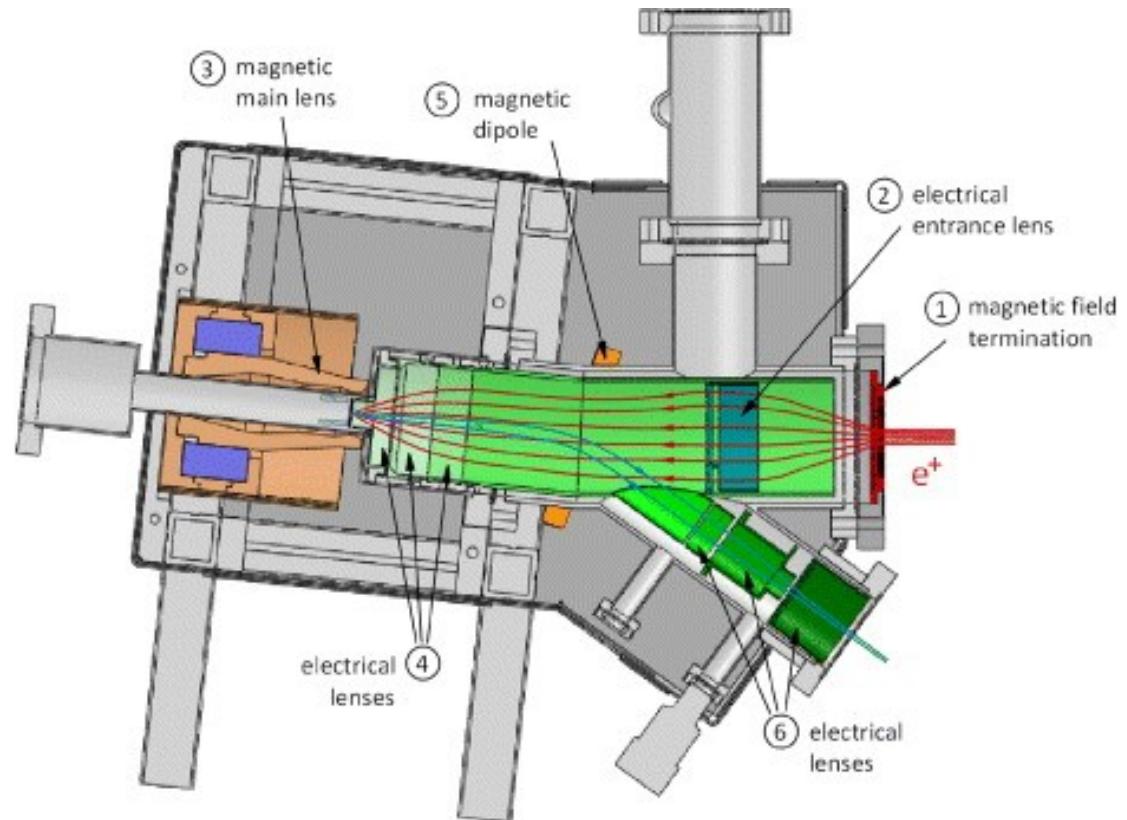
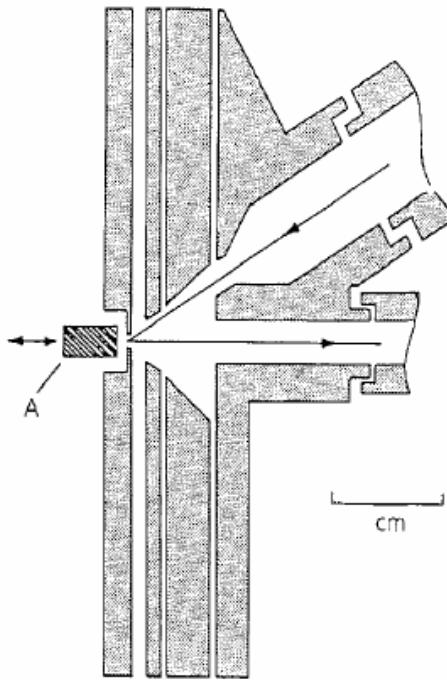
Positron microscope

- remoderation
 - electrostatic remoderator
 - reduction of beam spot size $\approx 10 \times$
- remoderator with magnetic lens
 - magnetic separation of primary beam and remoderated e^+
 - reduction of beam spot size $\approx 100 \times$



Positron microscope

- remoderation
 - electrostatic remoderator
 - reduction of beam spot size $\approx 10 \times$
- remoderator with magnetic lens
 - magnetic separation of primary beam and remoderated e^+
 - reduction of beam spot size $\approx 100 \times$



Positron microscope

- scanning positron microscope

- TU Munich

- focused pulsed slow e^+ beam

- spot size of focused beam $\approx 2 \mu\text{m}$

$$r_{opt} = \sqrt{\frac{f^2 \Delta E}{E} + \frac{C_s^2 R^6}{16 f^6}}$$

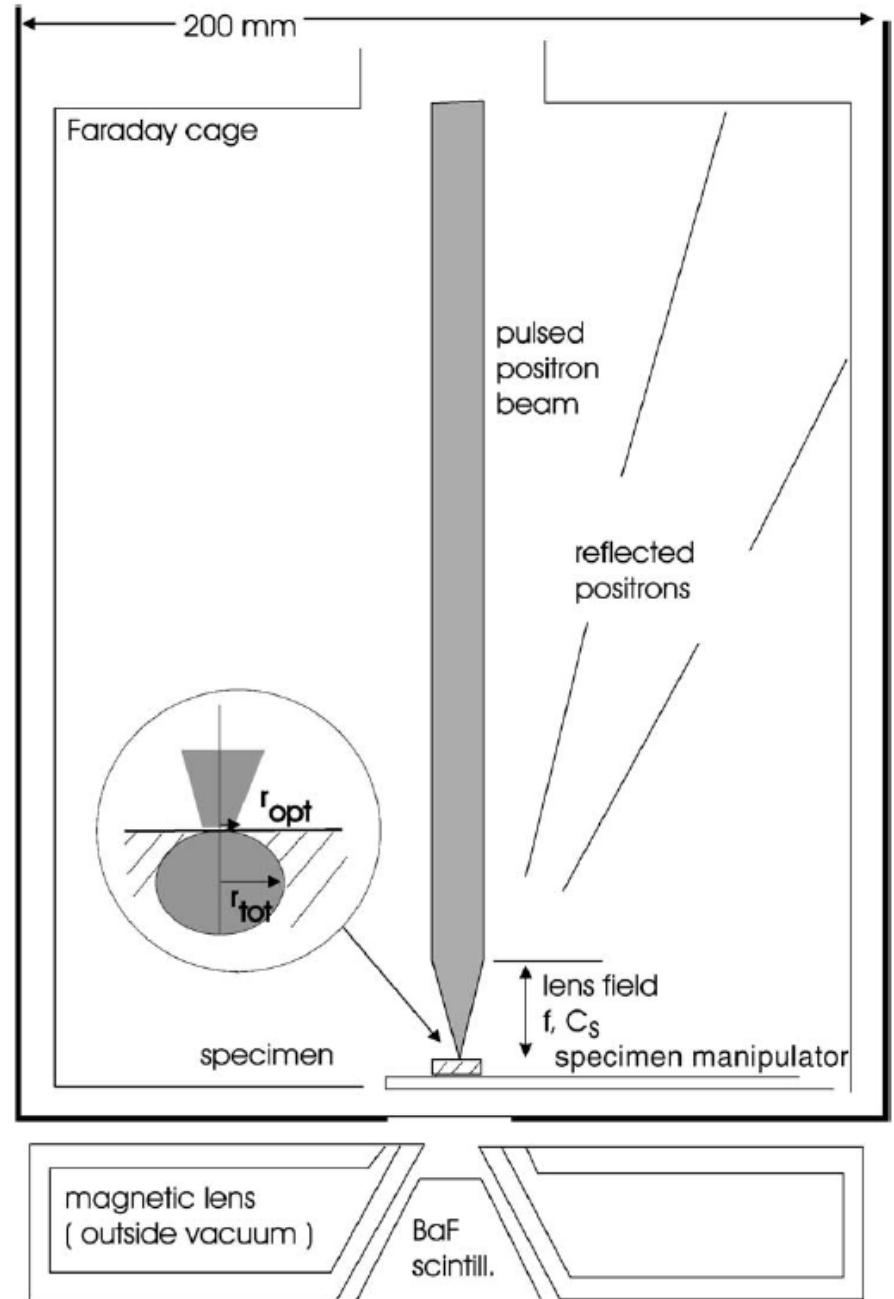
- ΔE – dispersion of transversal e^+ energy

- f – focused length of electrostatic lens

- C_s – spherical aberration

- R – beam radius

Kögel et al. Appl. Surf. Sci. 116, 108 (1997)



Positron microscope

- scanning positron microscope

- TU Munich

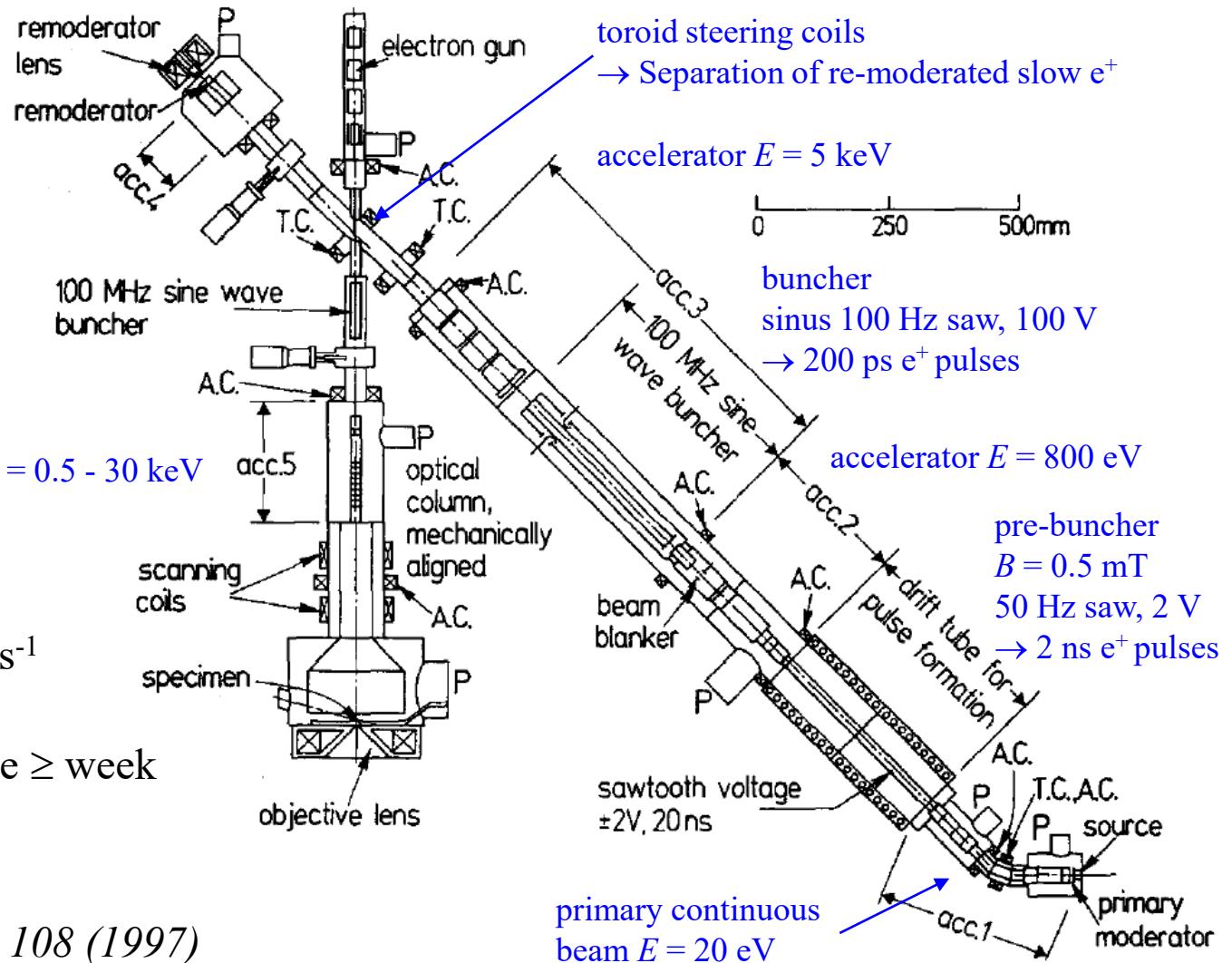
- focused pulsed slow e^+ beam

- beam spot size $\approx 2 \mu\text{m}$

- time resolution $\approx 250 \text{ ps}$

- coincidence count rate $\approx 500 \text{ s}^{-1}$

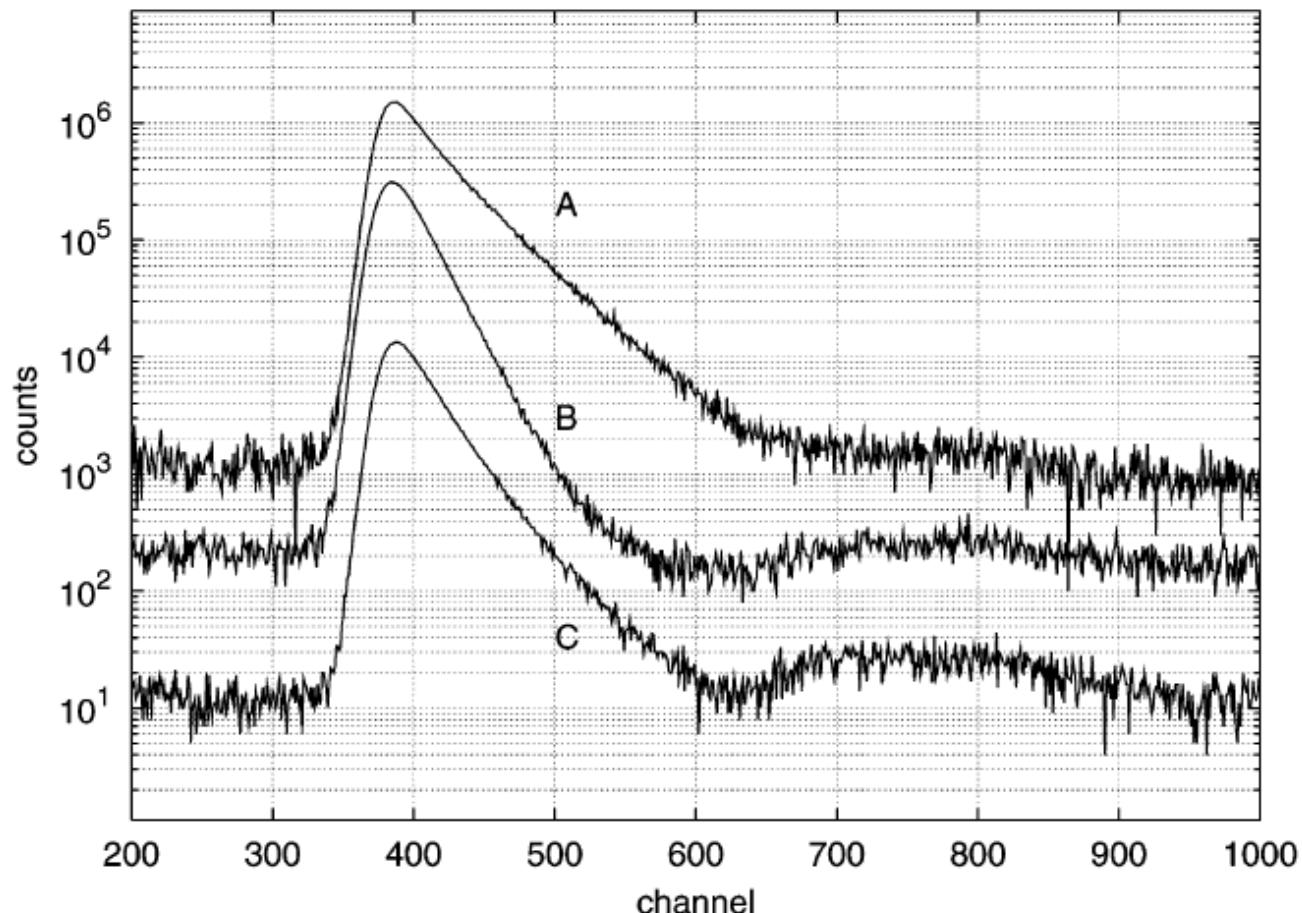
- collection time of single frame $\geq \text{week}$



Positron microscope

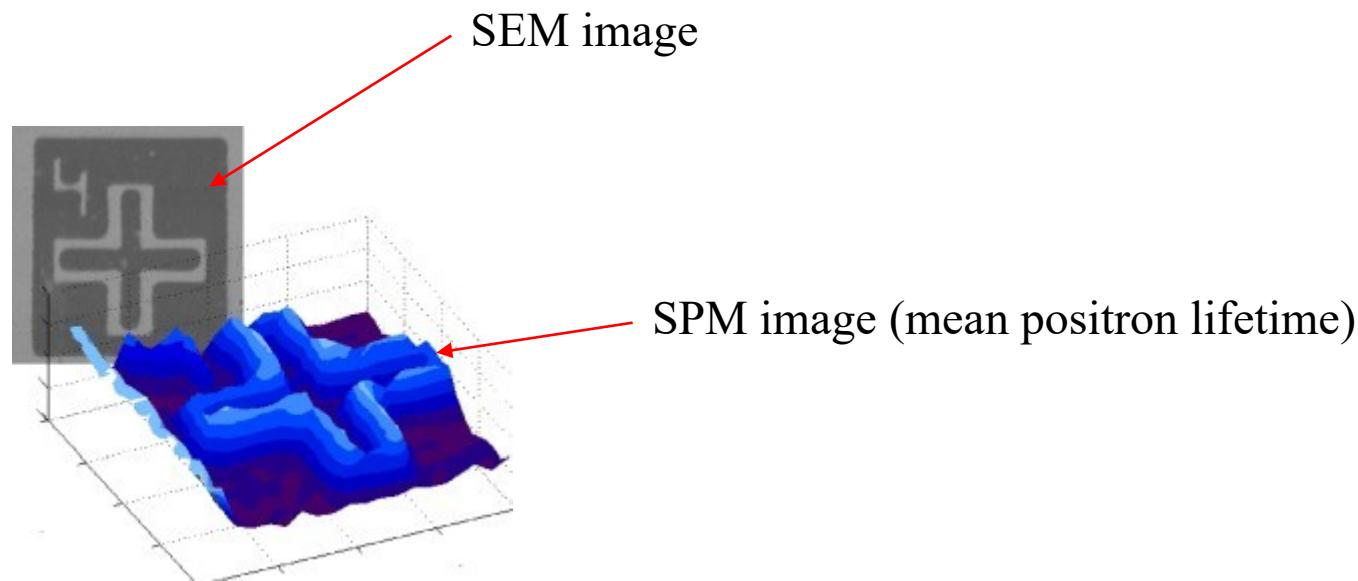
- scanning positron microscope
- TU Munich
- focused pulsed slow e^+ beam
- time resolution ≈ 250 ps

example of positron lifetime spectra measured on SPM, $E = 8$ keV



Positron mikroskope

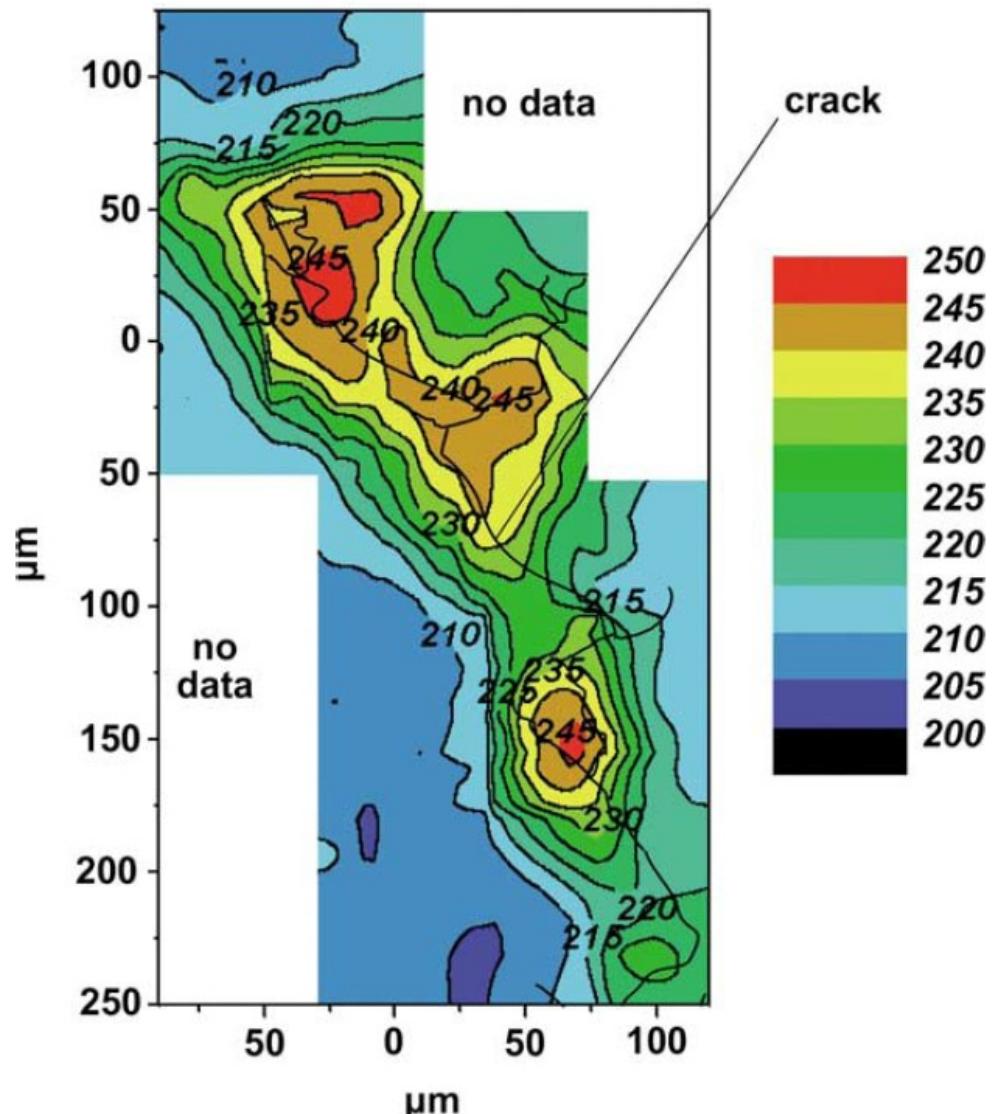
- scanning positron microscope
- TU Munich
- spatial resolution $\approx 2 \mu\text{m}$
- Si substrate with etched pattern



David et al. Phys. Rev. Lett. 87, 067402 (2001)

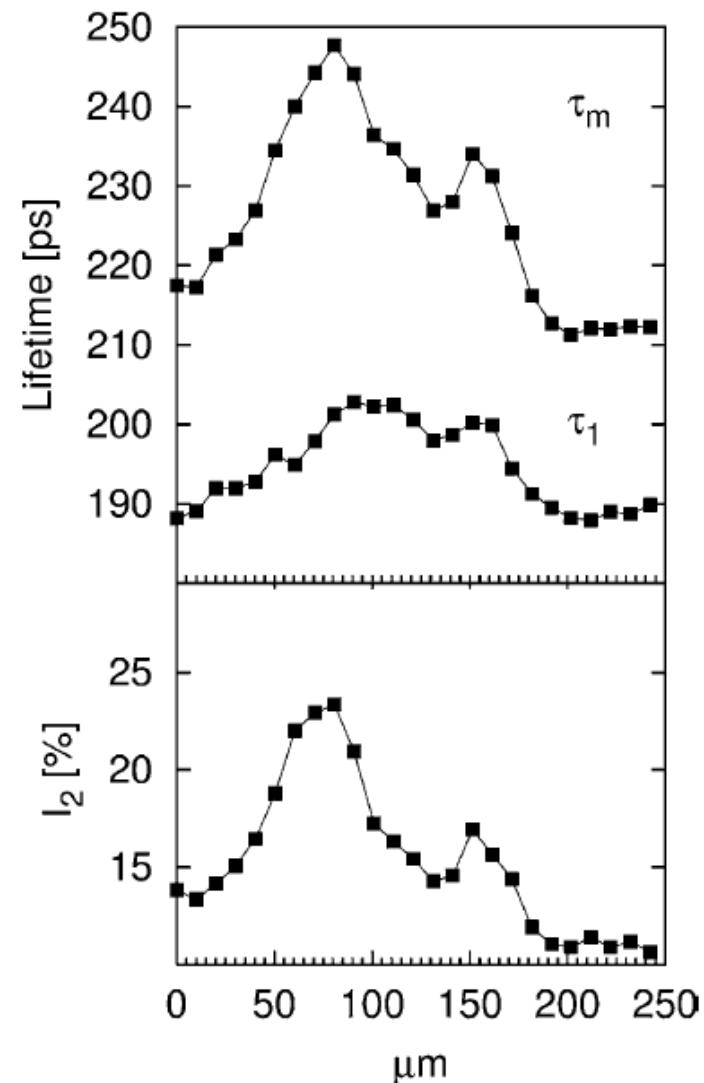
Positron microscope

- scanning positron microscope
- TU Munich
- spatial resolution $\approx 2 \mu\text{m}$
- Cu fatigue
- mapping using mean positron lifetime
- $E = 16 \text{ keV}$



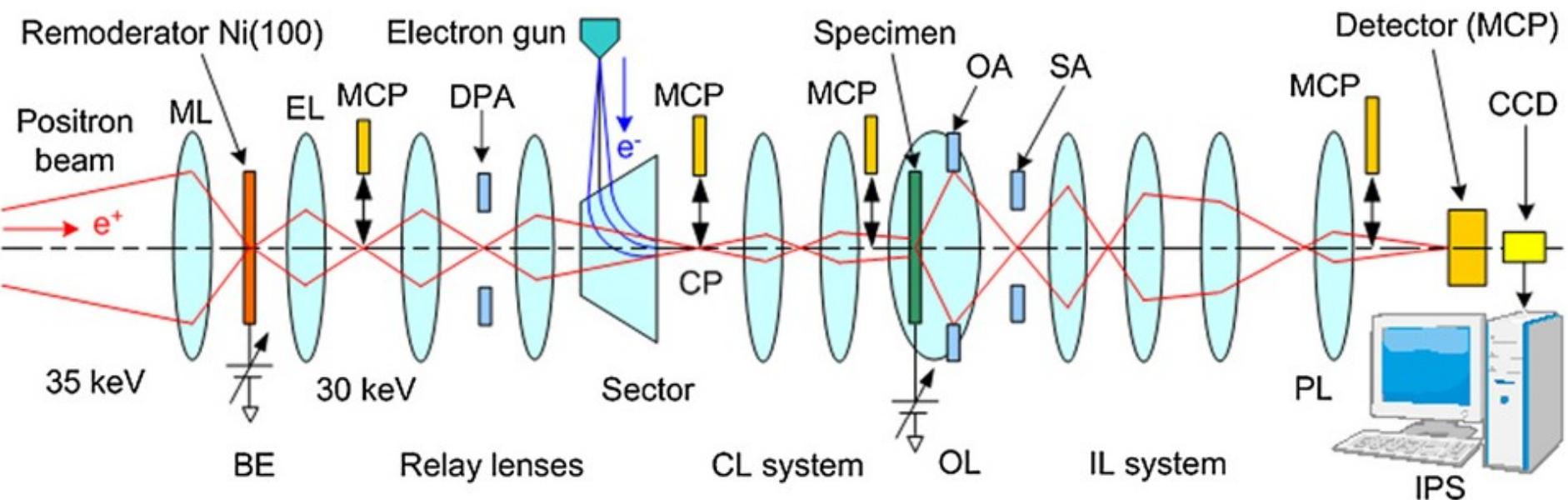
Positron microscope

- scanning positron microscope
- TU Munich
- spatial resolution $\approx 2 \mu\text{m}$
- Cu fatigue
- linear scan perpendicular to crack
- $E = 16 \text{ keV}$
- two-component decomposition, τ_2 fixed at 400 ps



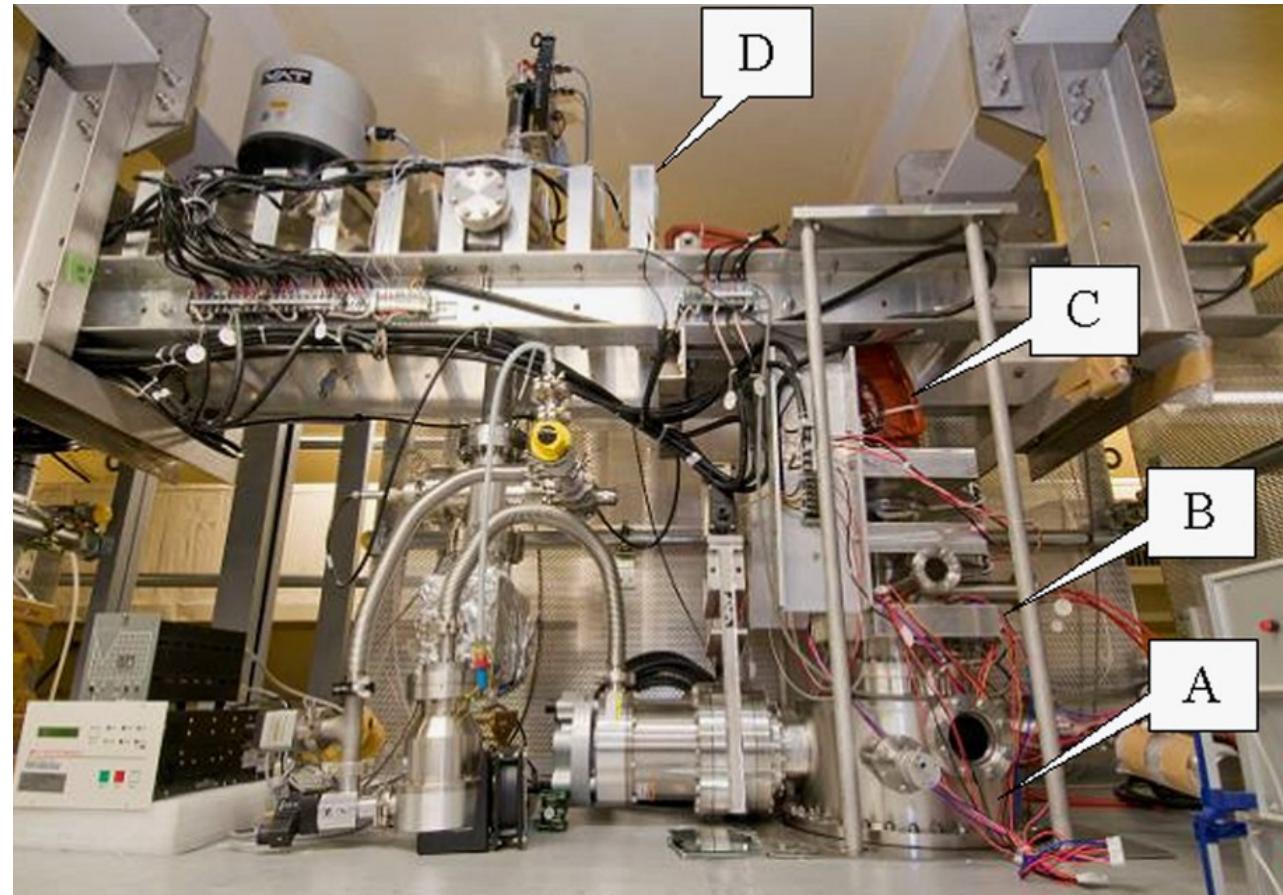
Positron microscope

- transmission positron microscope
- KEK Tsukuba
- positron source: LINAC



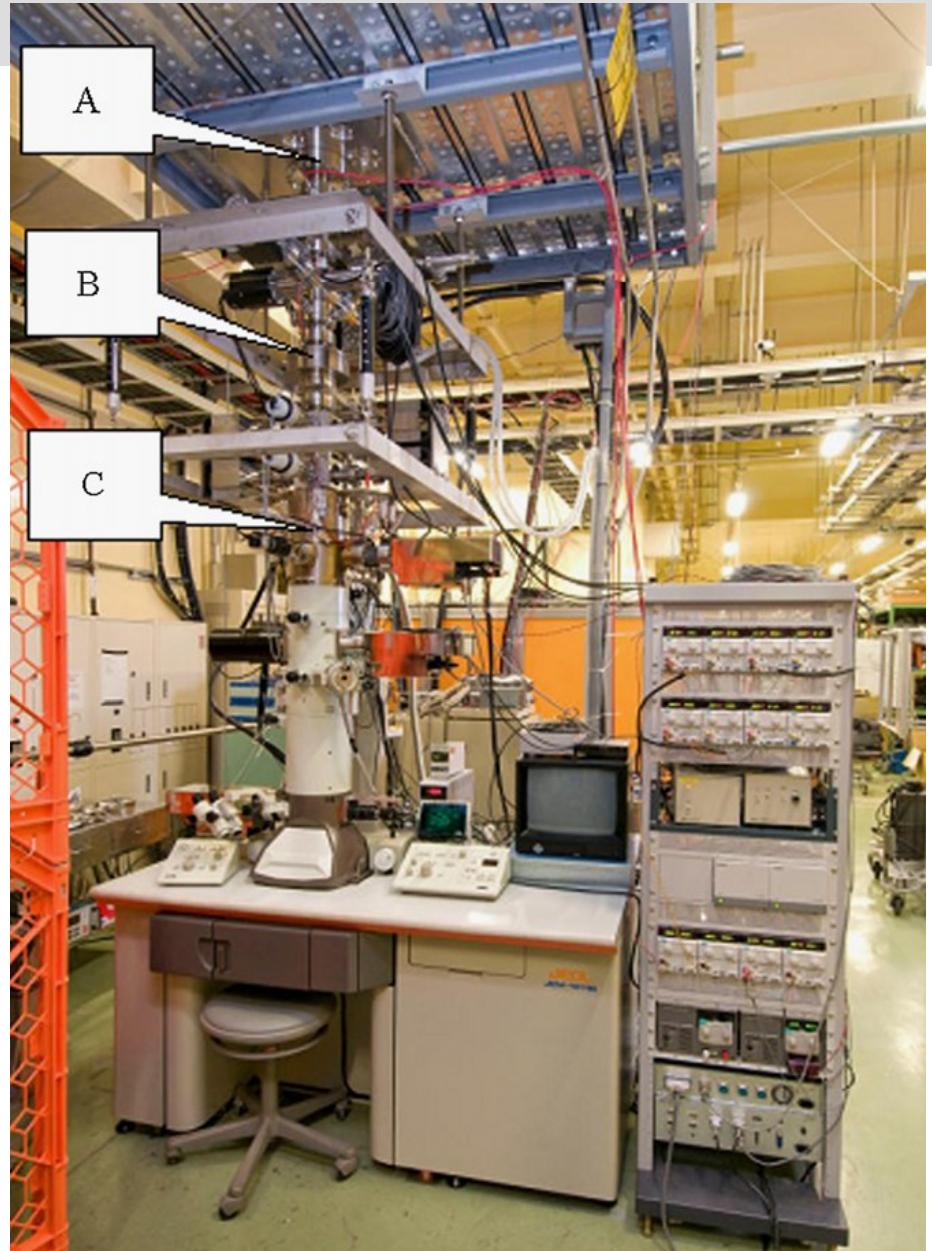
Positron microscope

- transmission positron microscope remoderator (brightness enhancer)
 - KEK Tsukuba
 - positron source: LINAC



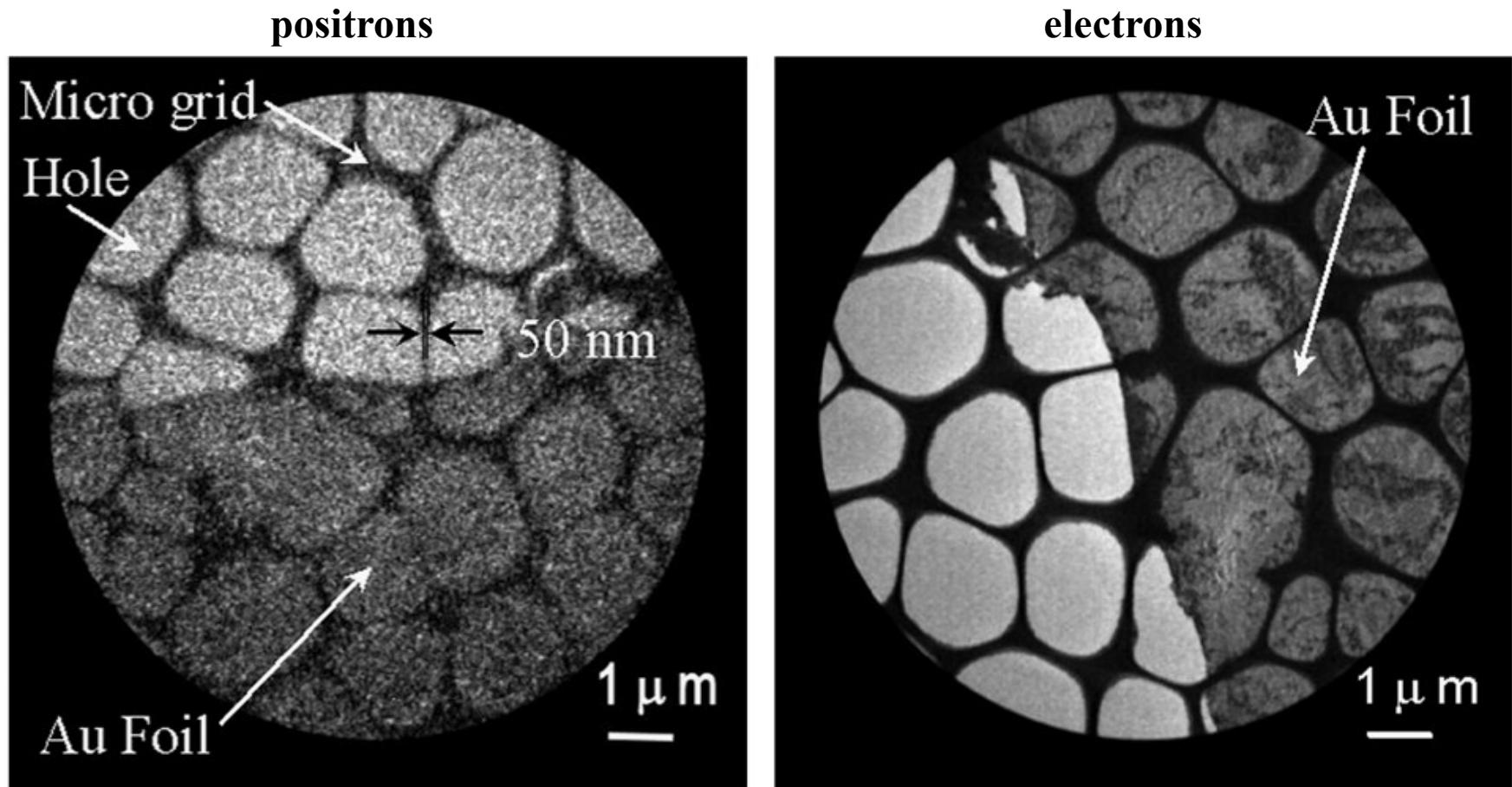
Positron microscope

- transmission positron microscope
- KEK Tsukuba
- positron source: LINAC



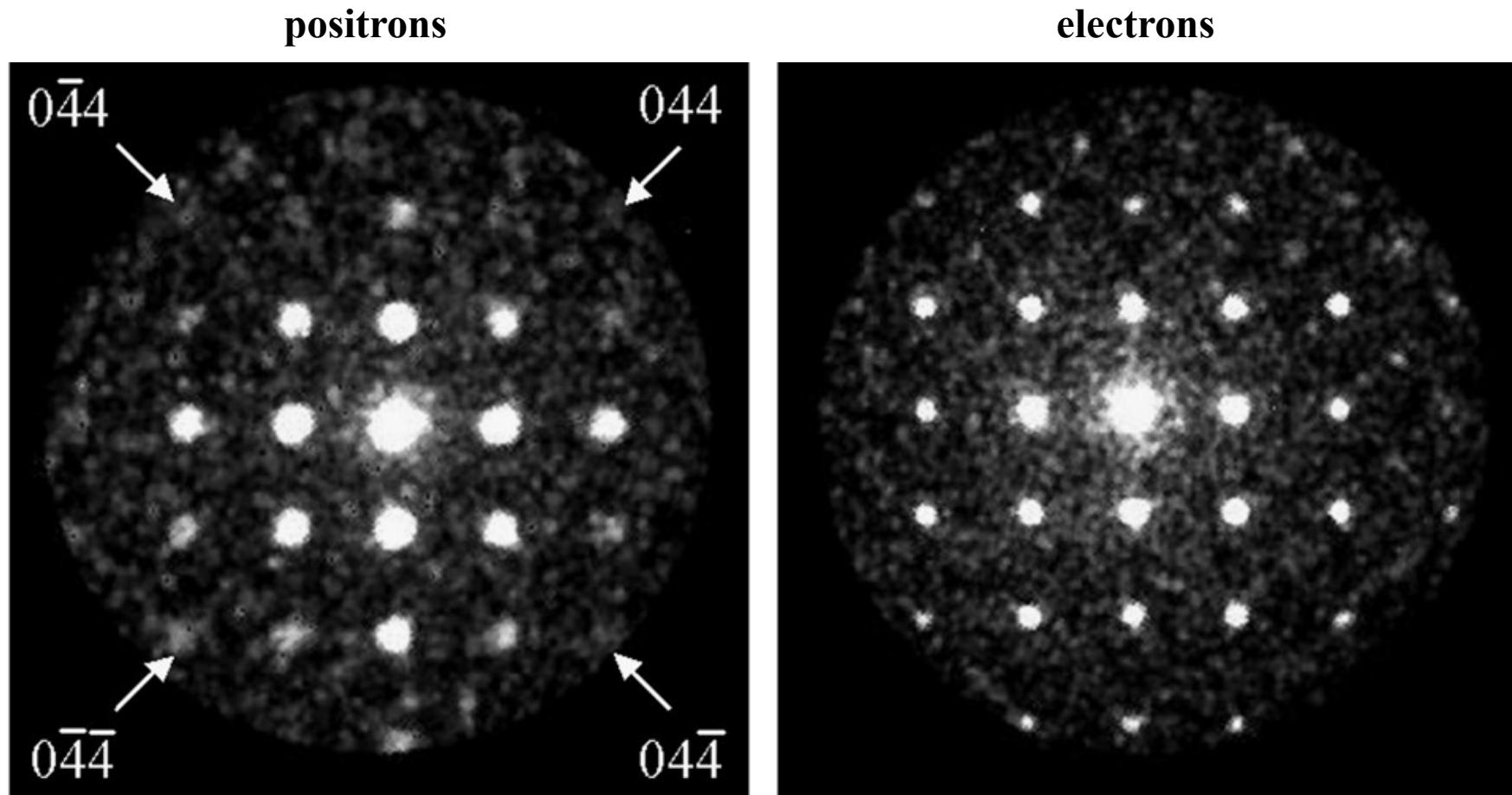
Positron microscope

- transmission positron microscope
- 10 nm Au (100) foil on a supporting Cu mesh



Positron microscope

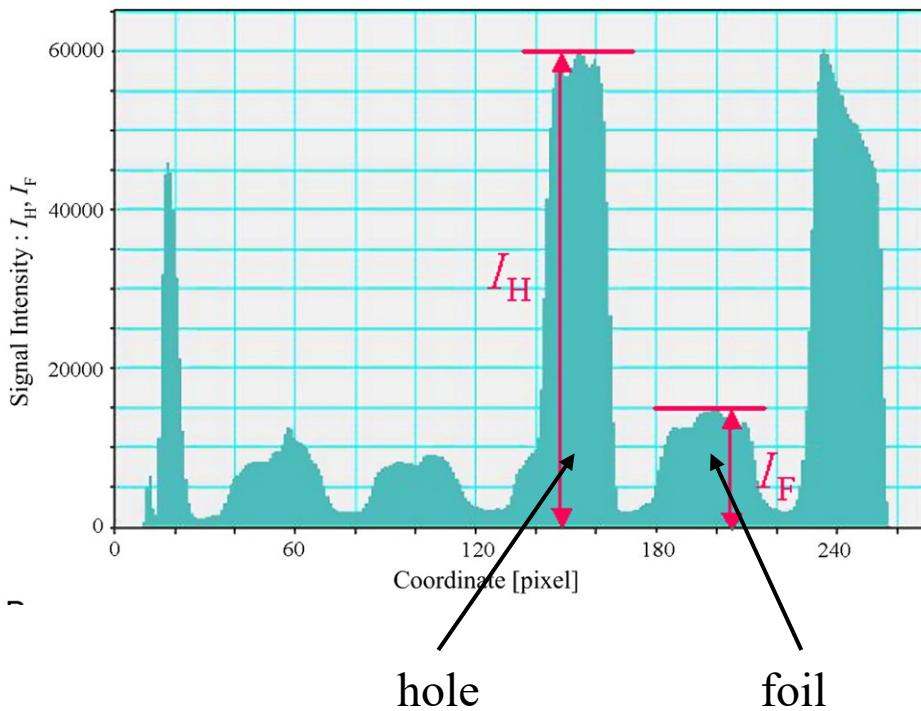
- transmission positron microscope
- 10 nm Au (100) foil on a supporting Cu mesh - diffraction



Positron microscope

- transmission positron microscope
- 35 nm Al foil on a supporting Cu mesh - transmittance

pozitrony



elektryny

